

WEBINAR ANNOUNCEMENT

Elionix ELS-G100 100 kV Electron Beam Lithography System – Enabling Nanotechnology

Devin K. Brown

Senior Research Engineer
Institute for Electronics & Nanotechnology
Georgia Institute of Technology



Date: May 7, 2020

Time: 11:00 AM – 12:00 PM (EDT)

Abstract: The Elionix ELS-G100 is a direct write electron beam lithography system that uses a 100 kV acceleration voltage and a 1.8 nm spot Gaussian beam to achieve nanometer scale resolution. The Elionix electron beam lithography tools are known for ultra-high precision to fabricate small nanostructures with excellent reliability. The ELS G-100 is capable of generating patterns with a line width of 5 nm. A 20bit DAC provides high beam positioning resolution. In addition, the laser interferometer with its reading resolution of 0.31 nm enables a stitching accuracy of 15 nm and overlay accuracy of 20 nm. The tool features a maximum field size of 1 mm and a scanning frequency of 100 MHz. Sample sizes can be handled from small millimeter size pieces up to full 8” diameter wafers. This 30-minute webinar will provide an overview of the ELS-G100 system with a discussion of key features and capabilities followed by time for Q & A.

Bio: Devin is currently a Senior Research Engineer in the Institute for Electronics and Nanotechnology. He has held that position since 2002. His research interests have included fabrication of nanoscale devices and nanoscale process development. He is currently pursuing a PhD in electrical and computer engineering and his thesis is on nano-newton force transduction. Prior to Georgia Tech, he was a Senior Yield Engineer at Intel Process Technology Development group in Hillsboro, Oregon from 1995 to 2002. His positions there included managing an Ion Implant process module initially and then later front end transistor performance process development. He graduated from Georgia Tech in 1995 with an MSEE and in 1993 with a BEE.

Who should attend: Faculty, scientists, engineers, researchers, and technical staff from university, company, or government labs who are interested in learning about how electron beam lithography capability might enable their research efforts.

Join the Online Event May 7th at this Link: <https://bluejeans.com/237855794>